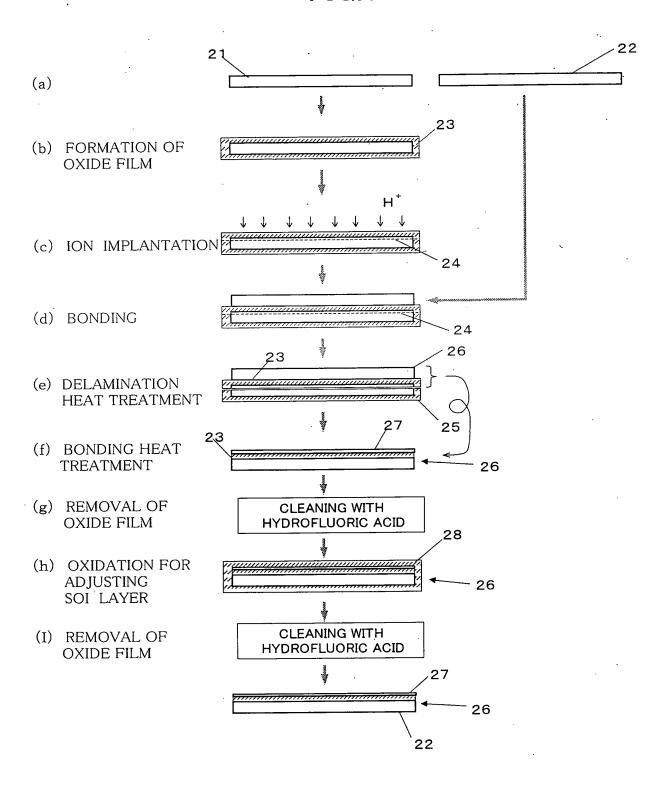
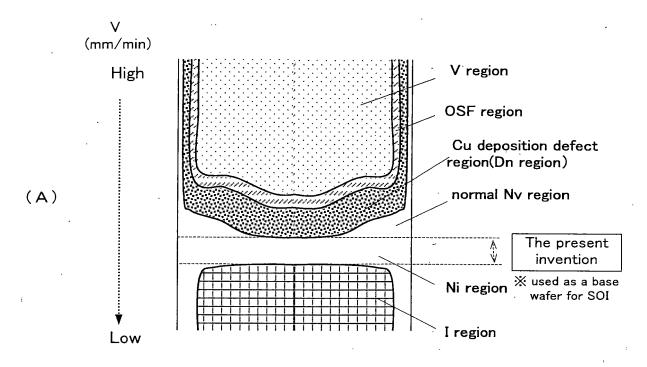
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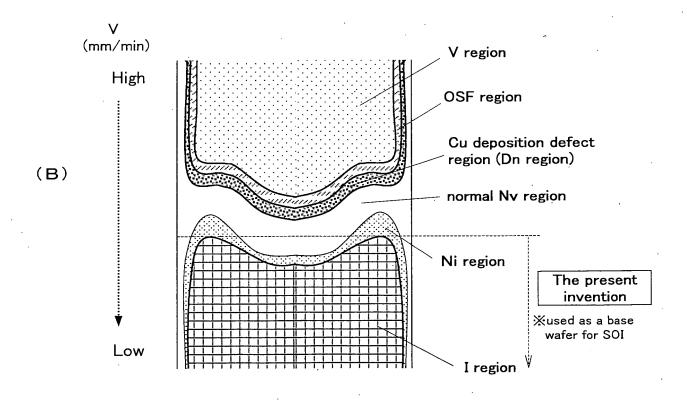
FIG.1



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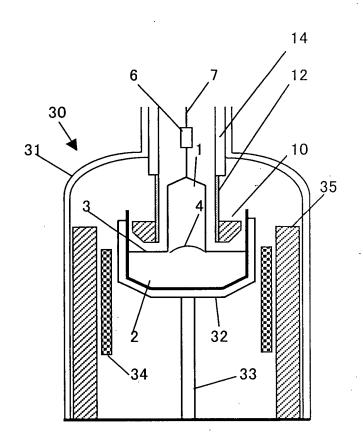
FIG. 2

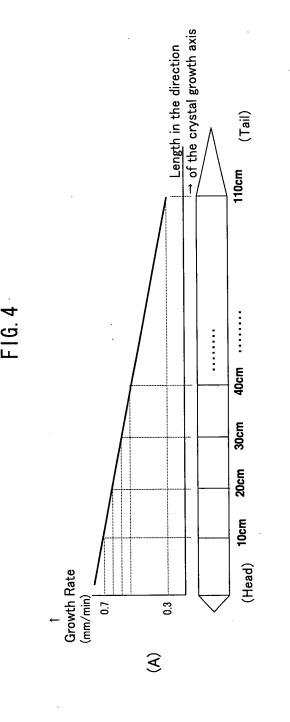


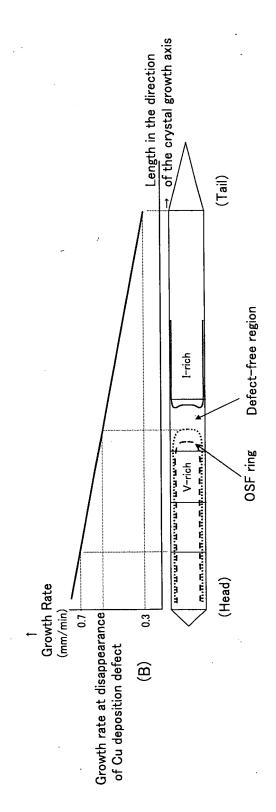


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FIG. 3

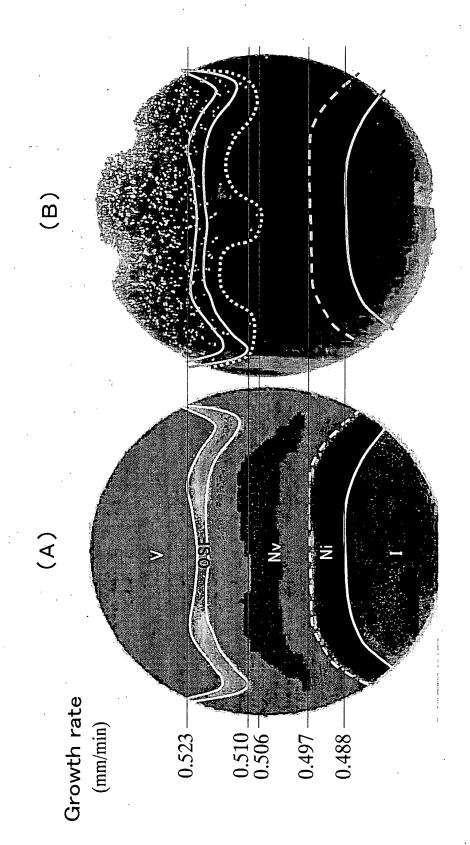




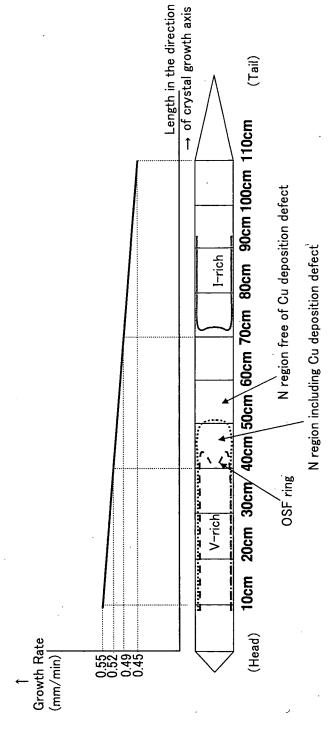


WLT map Cutting out in the size of 8" ϕ Cu deposition treatment Mirror polishing process Formation of oxide film

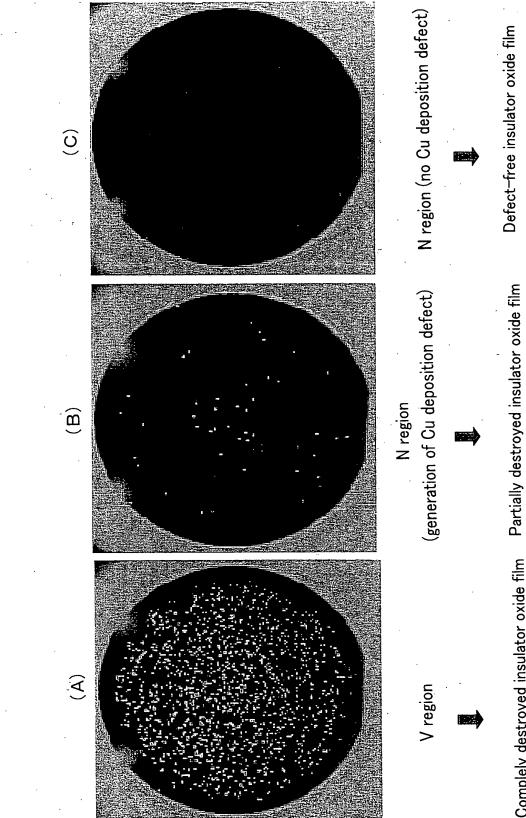
F1G. 5



F1G. 6



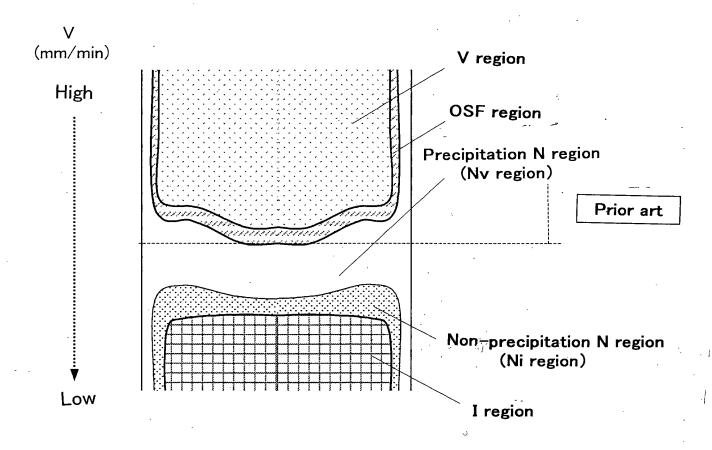
F16.



F16.8

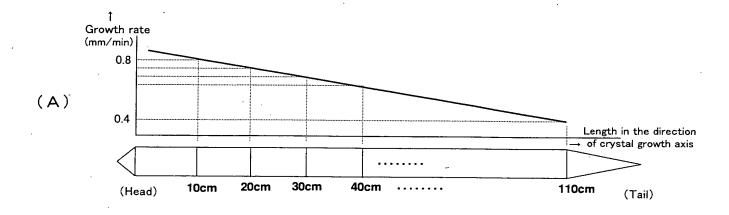
Complely destroyed insulator oxide film

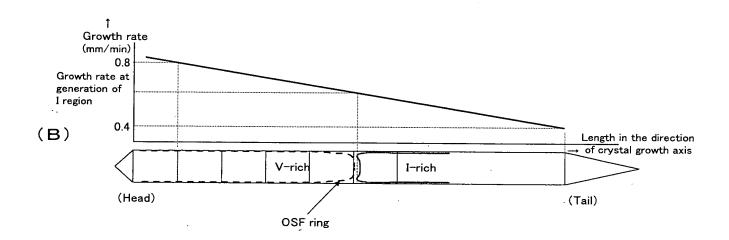
FIG. 9

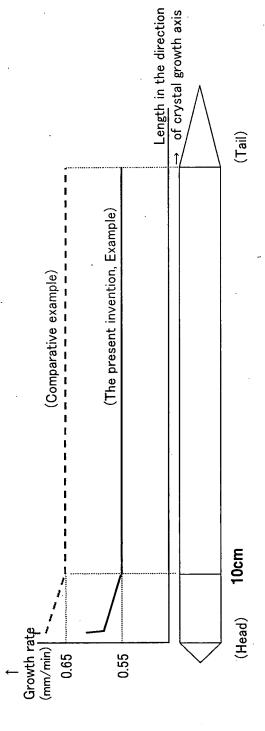


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FIG. 10

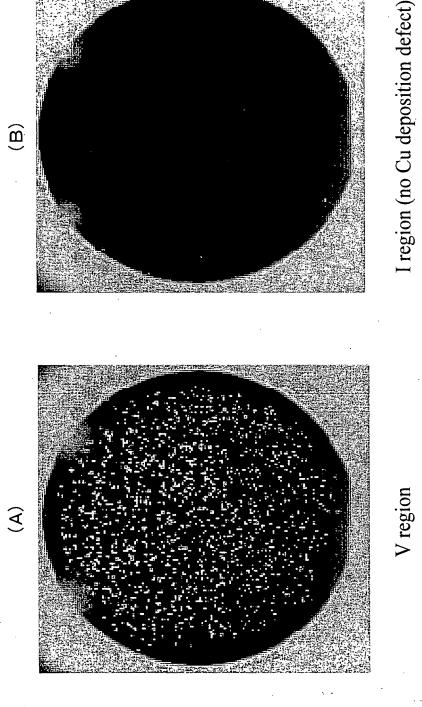






F1G. 1





Defect-free insulator oxide film

Completely destroyed insulator oxide film